

1FW/AF

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE



Art Unit: 2892

Examiner: Mr. William F. Kraig

In re PATENT APPLICATION of:

Applicant : Akira TAKAHASHI)
Serial No. : 10/798,482)
Filed : March 12, 2004)
For : DRY ETCHING METHOD FOR)
SEMICONDUCTOR DEVICE)
Attorney Ref. : OKI 414)

**AMENDMENT
AFTER
FINAL REJECTION**

September 9, 2008

Mail Stop AF
Director of Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is responsive to the Office Action of June 9, 2008, the period for reply to which has been set to expire on September 9, 2008.

A fee of \$None is also being submitted concurrently. Should this remittance be accidentally missing, however, or should any additional fees be needed, the Director may charge such fees to our Deposit Account number 18-0002.

Please amend the above-identified application as specified on the following pages, and then reconsider the application in view of the Remarks that are presented thereafter.